

Abstract of the Disclosure

An apparatus for measuring a gap between a mask and a substrate and a method thereof are provided. The apparatus includes a laser displacement sensor, 5 which is placed on a mask and a substrate spaced apart from each other by a predetermined gap, emits laser beams while moving onto the mask and the substrate in a horizontal direction and measures a gap between the mask and the substrate using a variation in distance values measured based on light-receiving positions of the laser beams that are reflected from the mask and the substrate and 10 return to their original positions, respectively.